

Amendment and Response  
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**Amendments to the Claims:**

This listing of claims will replace all prior versions, and listings, of claims in the application:

**Listing of Claims:**

1-26. (Cancelled)

27. (Currently amended) A method of fabricating a micro-mirror structure in a micro-mirror strip of micro-mirror structures comprising:

forming a pyramidal structure from a first substrate material; and  
defining electrodes on the pyramidal structure for positioning a mirror disposed adjacent to the pyramidal structure.

28. (Original) The method of claim 27, wherein forming the pyramidal structure comprises:  
anisotropic etching the pyramidal structure to form steps of various depths in the structure.

29. (Currently amended) The method of claim 27, wherein the electrodes include four electrodes and forming the electrodes further comprises ~~arranging~~ arranging each electrode on a different one of quadrants of the pyramidal structure.

30. (Original) The method of claim 28, wherein the steps are polygonal in shape.

31. (Currently amended) The method of claim 27, wherein the substrate material is a first substrate material and wherein a second substrate material is bonded to the first substrate material.

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32. (Previously presented) The method of claim 31, wherein the second substrate material is a silicon-on-insulator wafer and is bonded to the first substrate material with a device side facing the wafer.

33. (Previously presented) The method of claim 31, further comprising:

disposing a material to define the mirror in a surface of the second substrate material.

34. (Previously presented) The method of claim 31, further comprising:

defining sensors in the surface of the second substrate material.

35. (Currently amended) The method of claim 27, further comprising:

adding dam structures to ~~at least one of the substrate materials~~ material to isolate the micro-mirror structure from adjacent micro-mirror structures in a strip of micro-mirror structures.

36. (Previously presented) The method of claim 34, further comprising:

defining other electronic components of the micro-mirror structures in one of the substrate materials.

37. (Withdrawn) A hinge comprising:

a plurality of parallel hinge sections provided by vertical slots therein, the slots and parallel hinge sections being dimensioned to provide vertical and lateral stiffness to and a minimal torsion spring constant for the hinge.

38. (Currently amended) A micro-mirror assembly comprising:

a frame;

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an array of two-dimensional deflecting mirrors mounted in the frame; and  
blocking dams disposed between the mirrors to block viscous interaction between each of  
the two dimensional deflecting mirrors and adjacent ones of the two-dimensional deflecting  
mirrors in the array.